

ABSTRACT

SUBSTRATE CARRYING MECHANISM, SUBSTRATE CARRYING
METHOD AND RECORDING MEDIUM STORING PROGRAM
5 INCLUDING SET OF INSTRUCTIONS TO BE EXECUTED TO
ACCOMPLISH THE SUBSTRATE CARRYING METHOD

A substrate carrying mechanism measures accurately a
displacement of a substrate provided with a notch in its edge on
5 a holding fork when the substrate held by a holding fork is
carried, corrects accurately the displacement, and corrects the
state of the holding fork. The substrate carrying mechanism
includes: a base; a substrate holding member 3A placed on the
base and capable of holding a substrate W and of being
10 advanced and retracted relative to the base; four or more
detecting units 5 respectively for detecting different parts of the
edge of a substrate held by the substrate holding member 3A
when the substrate holding member 3A holding a substrate W is
retracted; and a controller that determines whether or not a
15 notch WN formed in the edge of the substrate W has been
detected by one of the detecting units 5, on the basis of
measurements measured by the four or more detecting units 5
and corrects an error in a transfer position where the substrate
is to be transferred to the succeeding processing unit on the
20 basis of measurements measured by the detecting units 5
excluding the one detecting unit 5 that has detected the notch
WN of the substrate W.

FIG. 7



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